



Thin Film Transistors: Material, Structure and Application

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Message from the Guest Editor

Dear Colleagues,

Since the first report on cadmium selenide thin-film transistors (TFTs) by Paul. K. Weimer in 1962, various semiconductor materials have been used for channel materials of TFTs such as amorphous silicon, polycrystalline silicon, organic semiconductors, and oxide semiconductors. To date, TFTs have been used for various applications such as active-matrix liquid crystal display, active-matrix organic light-emitting diode displays, X-ray detectors, chemical sensors, bio sensors, and memory devices. However, to use the TFTs in more diverse applications, it is crucial to further improve the electrical performance and stability of TFTs. This special issue calls for innovative latest research results on TFTs which can be helpful in expanding their application area.

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Guest Editor





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